

Supporting Information

Effect of Interlayer Spacing in Layered Perovskite on Resistive Switching Memory

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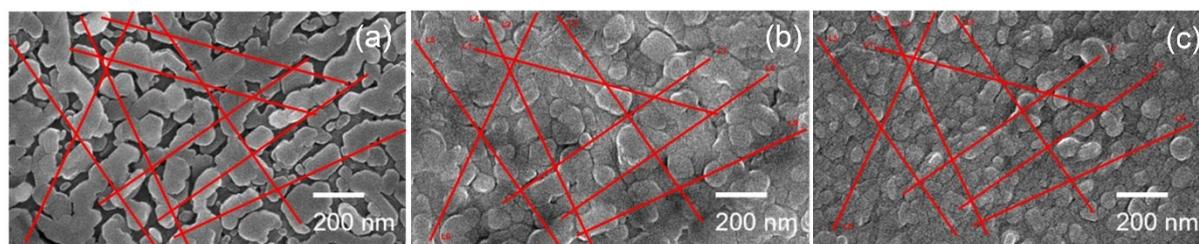


Figure S1. Line intercept method for estimating the average grain size of (a) $(\text{An})_2\text{PbI}_4$, (b) $(\text{BzA})_2\text{PbI}_4$, and (c) $(\text{PEA})_2\text{PbI}_4$ films. The average grain sizes of $(\text{An})_2\text{PbI}_4$, $(\text{BzA})_2\text{PbI}_4$, and $(\text{PEA})_2\text{PbI}_4$ films were determined to be 78.85 nm, 51.82 nm, and 47.92 nm, respectively.

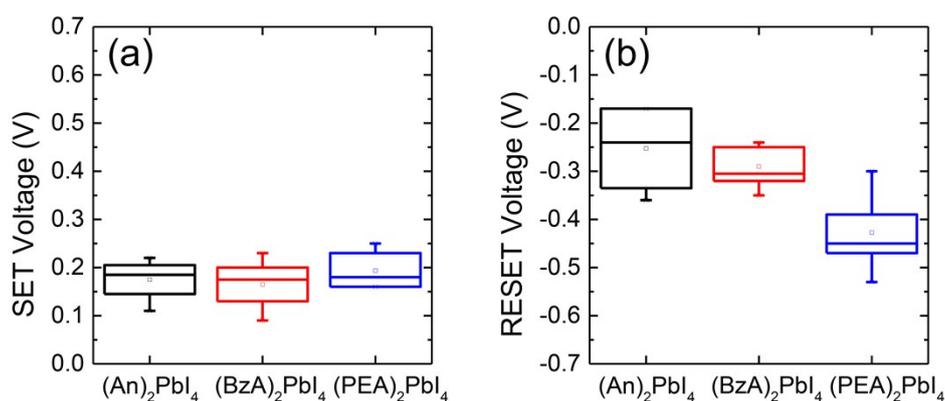


Figure S2. Box-plotted (a) SET and (b) RESET voltages for $(\text{An})_2\text{PbI}_4$, $(\text{BzA})_2\text{PbI}_4$, and $(\text{PEA})_2\text{PbI}_4$ resistive switching devices.

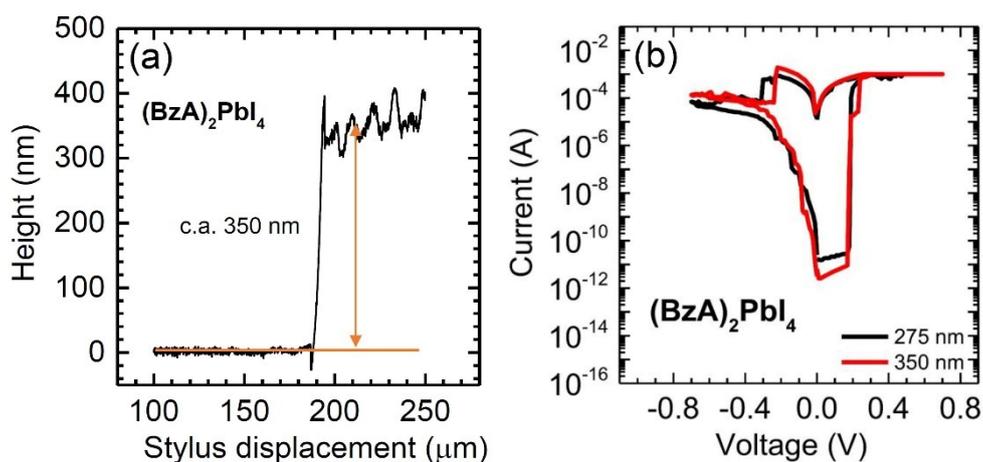


Figure S3. (a) Height of $(\text{BzA})_2\text{PbI}_4$ film measured by α -step profiler. (b) I-V characteristics of $(\text{BzA})_2\text{PbI}_4$ based memristor devices with different film thickness.

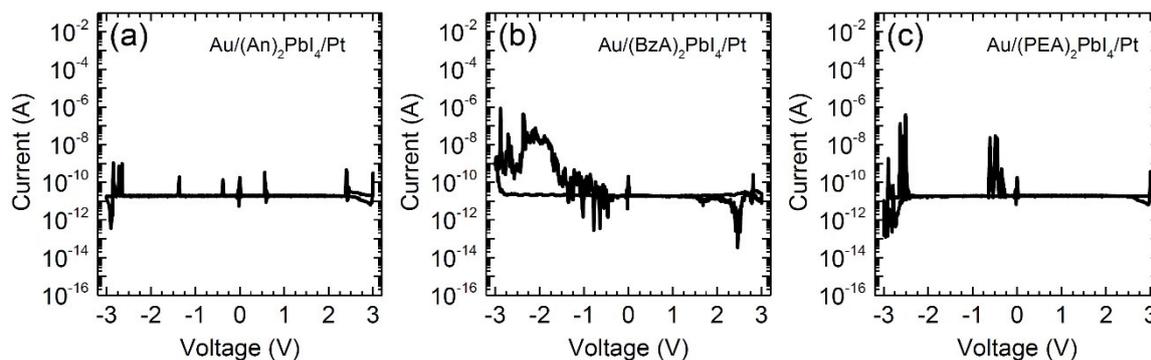


Figure S4. I-V characteristics of the Au/2D perovskite/Pt devices to analyze the electrochemical metallization mechanism. (a) $(\text{An})_2\text{PbI}_4$, (b) $(\text{BzA})_2\text{PbI}_4$, and (c) $(\text{PEA})_2\text{PbI}_4$.

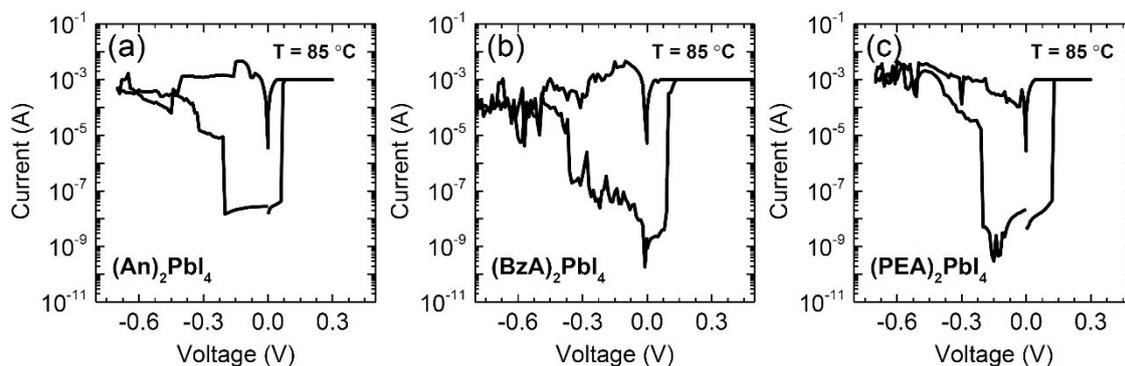


Figure S5. I-V characteristics of the Ag/PMMA/2D perovskite/Pt devices measured at 85 °C for (a) $(\text{An})_2\text{PbI}_4$, (b) $(\text{BzA})_2\text{PbI}_4$ and (c) $(\text{PEA})_2\text{PbI}_4$.

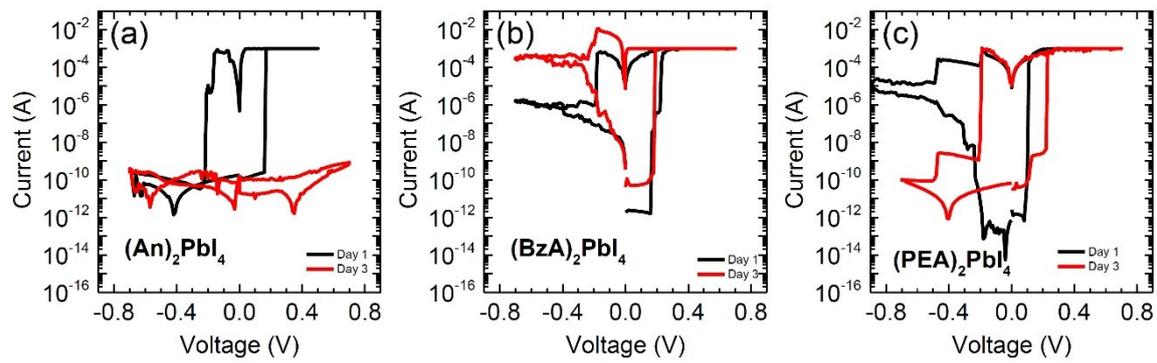


Figure S6. I-V characteristics of the Ag/PMMA/2D perovskite/Pt devices in ambient air condition under 50% humidity at 25 °C for (a) $(\text{An})_2\text{PbI}_4$, (b) $(\text{BzA})_2\text{PbI}_4$ and (c) $(\text{PEA})_2\text{PbI}_4$.